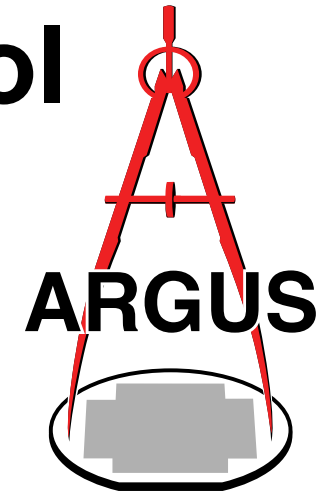
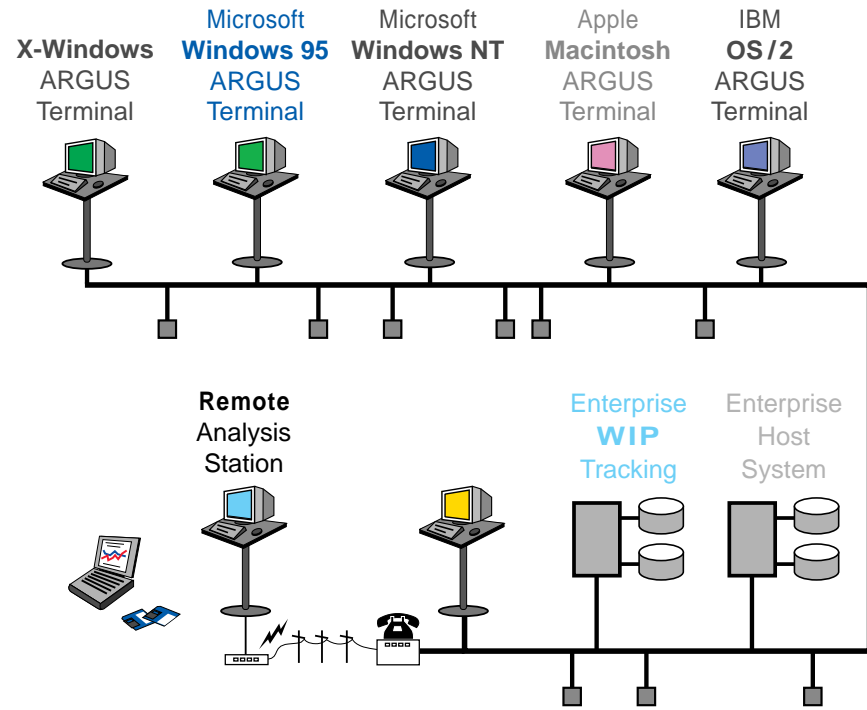


ARGUS Lithography Advanced Process Control



Enterprise Network



OptiTune

Capture production, distortion test and stage test data from metrology tools and utilize modeling to determine optimum equipment and process adjustments.

SPC

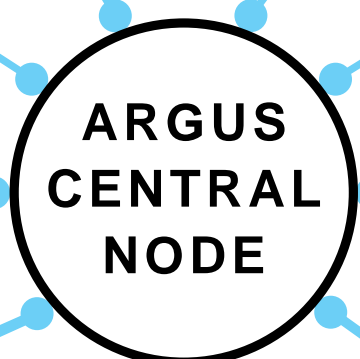
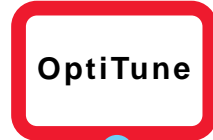
Track stepper and process performance from lot to lot and identify drift prior to yield loss. Facilitate failure analysis by identifying statistically significant relationships.

YieldMaster

Apply advanced statistical modeling algorithms to the estimation of yield for lithography lot disposition.

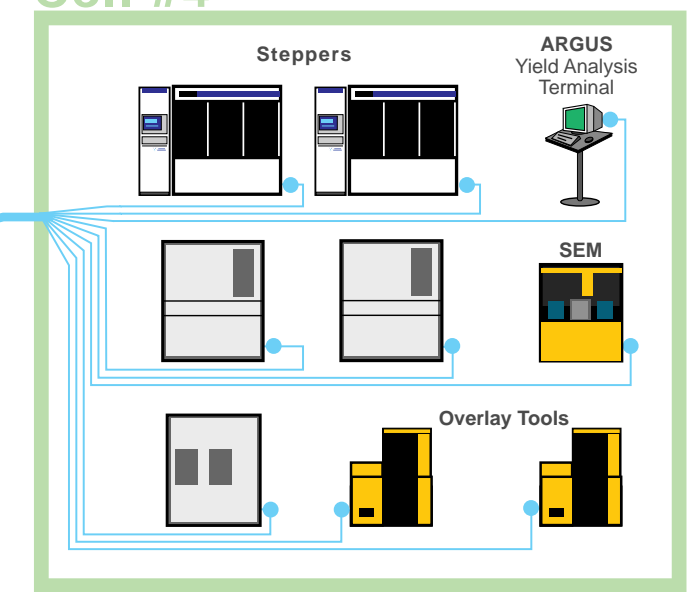
X-CD

Utilize causal analysis to identify the greatest sources of CD variation. Track CD performance of specific tools and the overall process.

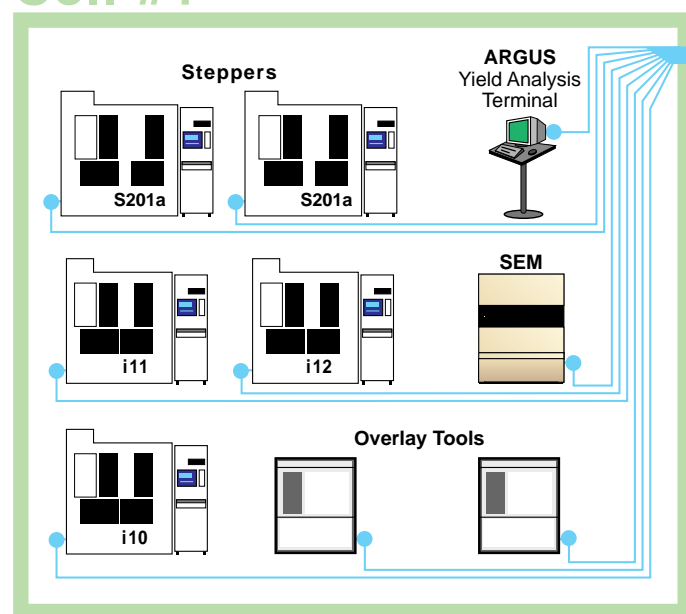


Bridge

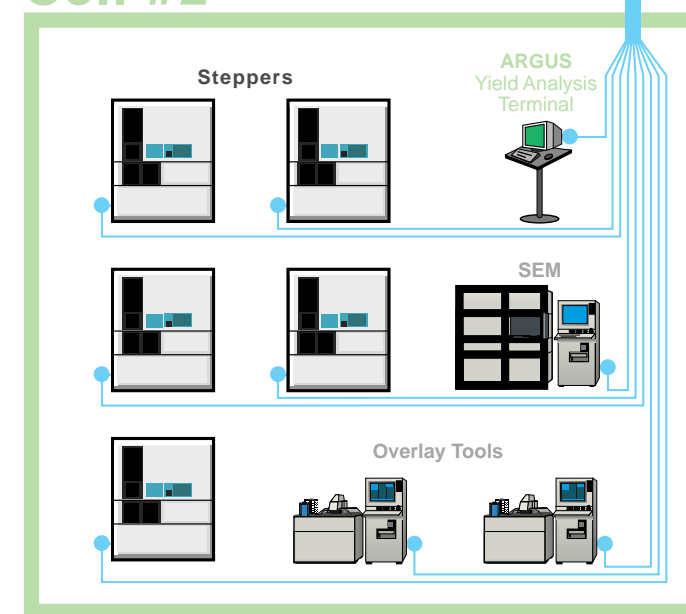
Cell #4



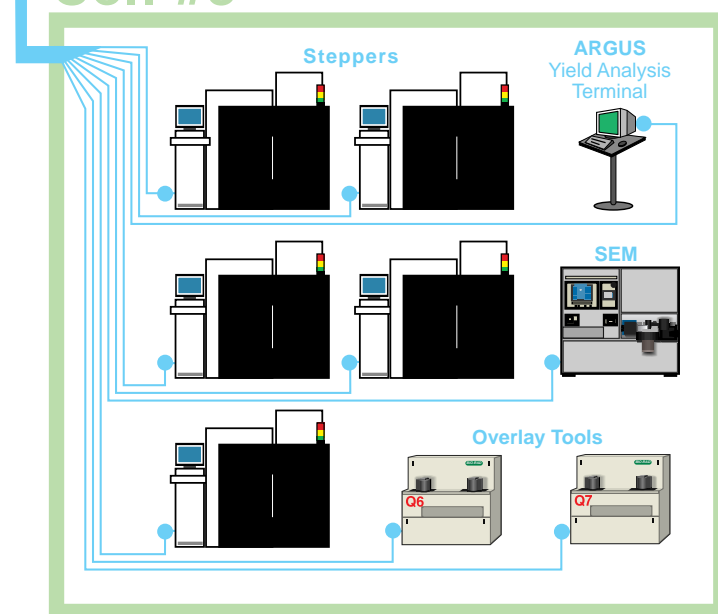
Cell #1



Cell #2



Cell #3



KEY

- Network with TLI's
- Functional Blocks
- Networked Computers
- Laptop system
- Modem or WAN link